

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE (REV.7-80) PATENT AND TRADEMARK OFFICE				Atty. Docket No. GB 010043		Serial No.	
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				Applicant Frank W. ROHLFING			
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JCS79 U.S. PTO
 10/099680
 03/15/02

U.S. PATENT DOCUMENTS													
Ex. Int.		Document Number							Date	Name	Class	Sub-class	Filing Date If Approp.
<i>HL</i>	AA	5	6	1	2	2	3	4	3/18/97	HA	437	40	
<i>HL</i>	AB	5	1	3	0	8	2	9	7/14/92	SHANNON	359	59	
<i>HL</i>	AC	5	7	8	6	2	4	1	7/28/98	SHIMADA	438	163	
	AD												
	AE												
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		Document Number							Date	Country	Class	Sub-class	Trans.			
		E	P	0	6	2	9	0	0	3					Yes	No
<i>HL</i>	AG	E	P	0	6	2	9	0	0	3	12/14/94	EUROPEAN	H01L	29/784	X	
<i>HL</i>	AH	G	B	2	3	2	6	0	1	9	12/9/98	GREAT BRITAIN	H01L	29/786	X	
<i>HL</i>	AI	0	8	2	9	3	6	1	2	A	11/5/96	JAPAN	H01L	29/786	X	
<i>HL</i>	AJ	0	7	1	3	1	0	2	7	A	5/19/95	JAPAN	H01L	29/786	X	
<i>HL</i>	AK	0	6	3	3	3	9	4	1	A	12/2/94	JAPAN	H01L	21/336	X	

OTHER (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>HL</i>	AL	"Structural fabrication using caesium chloride island arrays as resist in a fluorocarbon reactive ion etching plasma" by S. Tsuchiya, M. Green and R R A Syms in Electrochemical and Solid-State Letters 3, 44-46 (2000)
<i>HL</i>	AM	"Mesoscopic hemisphere arrays for use as resist in structure fabrication" by M Green and T J Tsuchiya, in Vac. Sci. and Tech. B17 2074-2083 (1999)
<i>HL</i>	AN	"Formation of silicon islands on a silicon on insulator substrate upon thermal annealing" by B Leggrannd, V. Agache, J P Nys, V. Senez and D. Stievenard, in Appl. Phys. Lett., 76(22) 3271 (2000).

Lawrence Schilling *8/20/02*

***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

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														Yes	No	
<i>AG</i>	AG	0	9	1	4	8	2	6	6	A	6/6/97	JAPAN	H01L	21/266	X	
	AH															
	AI															
	AJ															
	AK															

OTHER (Including Author, Title, Date, Pertinent Pages, Etc.)	
<i>AL</i>	"Nanostructure array fabrication with a size-controllable natural lithography" by C. Haginoya, M. Ishibashi and K. Koike, in Appl. Phys. Lett., 71(20 2934 (1999)
<i>AM</i>	"Quantum pillar structures fabricated on n ⁺ gallium arsenide fabricated using 'natural' lithography" by M. Green, M. Gargia-Parajo, F. Khaleque and R. Murray, in Applied Physics Letters 63, 264-266 (1993).
<i>AN</i>	"Micellar inorganic-polymer hybrid systems - a tool for nanolithography" by J P Spatz, T. Herzog, S.J.P. Spatz, T. Herzog, S. Mößmer, P. Ziemann and M. Möller, in Advanced Materials 11(2), 149 (1999).
<i>hanna Schütz</i> 8/20/02	
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FOREIGN PATENT DOCUMENTS												
	AG	AH	AI	AJ	AK	Document Number	Date	Country	Class	Sub-class	Trans.	
											Yes	No

OTHER (Including Author, Title, Date, Pertinent Pages, Etc.)		
AL <i>[Signature]</i>	AM <i>[Signature]</i>	"Fabrication of quasi-zero-dimensional submicron dot array and capacitance spectroscopy in a GaAs/AlGaAs heterostructure", by H. Fang, R. Zeller and P. J. Stiles, in Applied Physics Letters, 55(14), 1433 (1989).
AN		"Fabrication of silicon cones and pillars using rough metal films as plasma etching masks", by K. Seeger and R.E. Palmer, in Applied Physics Letters, 74(11), 1627 (1999).

<i>hanna Schutz</i>	<i>8/20/02</i>
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